

UNITED STATES DEPARTMENT OF COMMERCE United States Patent and Trademark Office Address: COMMISSIONER FOR PATENTS P.O. Box 1450 Alexandria, Virginia 22313-1450 www.uspto.gov

BIB DATA SHEET

CONFIRMATION NO. 3841

APPLICANTS Hiroki Nakamura, Chiba, JAPAN; Toshinori Takagi, Kyoto, JAPAN; Toshinori Takagi, Kyoto, JAPAN; This application is a 371 of PCT/JP05/01174 01/21/2005 ** FOREIGN APPLICATIONS *** IF REQUIRED, FOREIGN FILING LICENSE GRANTED ** 08/28/2007 Foreign Priority claimed	SERIAL NUM	IBER	FILING O		(c) CLASS			GROUP ART UNIT			ATTORNEY DOCKET	
APPLICANTS Hiroki Nakamura, Chiba, JAPAN; Toshinori Takagi, Kyoto, JAPAN; **CONTINUING DATA ******************************** This application is a 371 of PCT/JP05/01174 01/21/2005 **FOREIGN APPLICATIONS ************************************	10/500 100			_		118		1712				
Hiroki Nakamura, Chiba, JAPAN; Toshinori Takagi, Kyoto, JAPAN; *** CONTINUING DATA **********************************		RUL										
This application is a 371 of PCT/JP05/01174 01/21/2005 *** FOREIGN APPLICATIONS ************************************	Hiroki Nakamura, Chiba, JAPAN;											
JAPAN 2004-014341 01/22/2004 *** IF REQUIRED, FOREIGN FILING LICENSE GRANTED **	This application is a 371 of PCT/JP05/01174 01/21/2005											
Foreign Priority claimed Yes No 35 USC 119(a-d) conditions met Yes No No Note of Note	JAPAN 2004-014341 01/22/2004											
35 USC 119(a-d) conditions met Yes No Verified and Acknowledged												
Acknowledged Examiner's Signature Initials JAPAN 8 16 2 ADDRESS Quarles & Brady 411 E. Wisconsin Avenue Milwaukee, WI 53202 UNITED STATES TITLE Vacuum Deposition Method and Sealed-Type Evaporation Source Apparatus for Vacuum Deposition	35 USC 119(a-d) conditions met ✓ Yes ☐ No ☐			☐ Met af Allowa	ter ince		_	_			INDEPENDENT CLAIMS	
Quarles & Brady 411 E. Wisconsin Avenue Milwaukee, WI 53202 UNITED STATES TITLE Vacuum Deposition Method and Sealed-Type Evaporation Source Apparatus for Vacuum Deposition				Tnitials		JAPAN		8	16		2	
411 E. Wisconsin Avenue Milwaukee, WI 53202 UNITED STATES TITLE Vacuum Deposition Method and Sealed-Type Evaporation Source Apparatus for Vacuum Deposition	ADDRESS											
Vacuum Deposition Method and Sealed-Type Evaporation Source Apparatus for Vacuum Deposition	411 E. Wisconsin Avenue Milwaukee, WI 53202											
	TITLE											
	Vacuum Deposition Method and Sealed-Type Evaporation Source Apparatus for Vacuum Deposition											
☐ All Fees		☐ All Fees										
□ 1.16 Fees (Filing)		FEES: Authority has been given in Paper No. to charge/credit DEPOSIT ACCOUNT						☐ 1.16 Fees (Filing)				
FILING FEE RECEIVED No to charge/credit DEPOSIT ACCOUNT 1.17 Fees (Processing Ext. of time)	FILING FEE							☐ 1.17 Fees (Processing Ext. of time)				
1030 No for following:	_							☐ 1.18 Fees (Issue)				
□ Other								☐ Other	☐ Other			
☐ Credit								☐ Credit				